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520.36449VX1

**UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: TAGUCHI et al

Serial No.: 10/656,221

Filed: September 8, 2003

For: Inspecting Method And Apparatus For Repeated  
Micro-Miniature Patterns

Art Unit: 2623

Examiner: S. Ahmed

**AMENDMENT**

Mail Stop: Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 1, 2005

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated December 1, 2004. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.